

Applicants hereby amend the paragraph on page 27, beginning at line 10 of page 11 of the Preliminary Amendment filed on July 11, 2005 as follows:

Referring to FIG. 45, the gas sensor may have a heater for the required working temperatures, which may be above 100 °C. The chip in which the gas sensor is embodied may need to be heated to over 100 °C, because absorbed water on the surface of the gas-sensitive film 4 may otherwise hinder the gas reaction. The resistive heater may be buried in the substrate 1 or structured on the surface. Because the sensitivity of semiconductor gas sensors may be a function of temperature, the heater can be controlled. To this end, the sensor chip may have a temperature sensor whose signal can be used to acquire the actual temperature.